



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Kiyoshi IRINO

Serial No.: 09/428,052

Group Art Unit: 2815

Filed: October 27, 1999

Examiner: J. Diaz

For: METHOD OF FABRICATING A SEMICONDUCTOR DEVICE CONTAINING NITROGEN IN A GATE OXIDE FILM (AS AMENDED)

PETITION FOR EXTENSION OF TIME

Director of Patents and Trademarks
Washington, D.C. 20231
Sir:

July 7, 2000

Applicants petition the Commissioner of Patents and Trademarks to extend the time for response to the Office Action dated March 9, 2000, for one-month from June 9, 2000, to July 9, 2000.

Attached please find a check in the amount of \$110.00 to cover the cost of the one month extension. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 01-2340. Two copies of this paper are enclosed herewith.

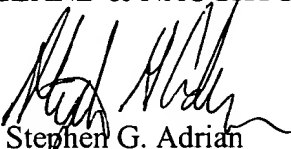
Respectfully submitted,

ARMSTRONG, WESTERMAN, HATTORI,
McLELAND & NAUGHTON

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Stephen G. Adrian
Attorney for Applicants
Reg. No. 32,878

Atty. Docket No. 970901A
1725 K Street, N.W., Suite 1000
Washington, DC 20006
Tel: (202) 659-2930
Fax: (202) 887-0357
SGA/arf

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